

# **Toward the 3D-SiP Era with New Technologies**

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(Sharp/Japan)

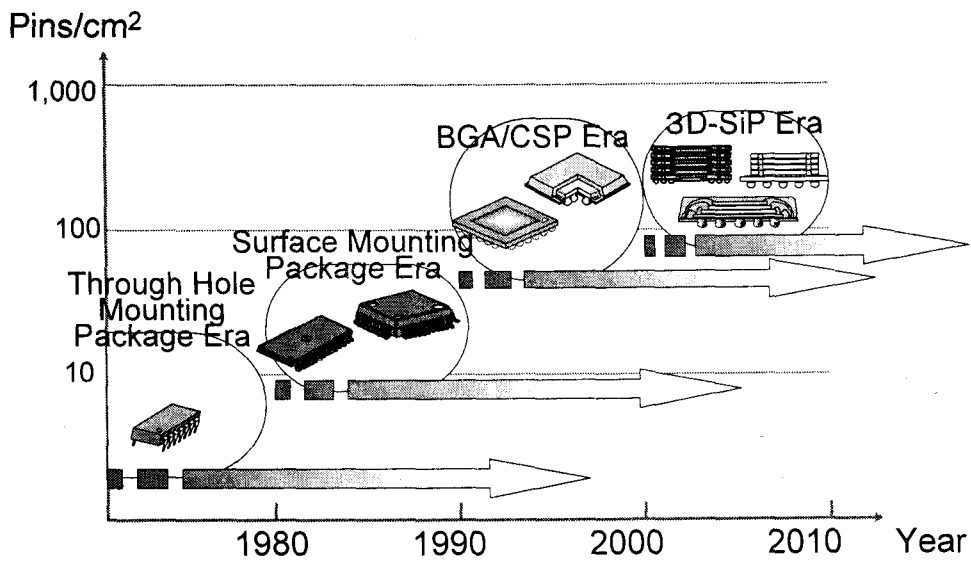




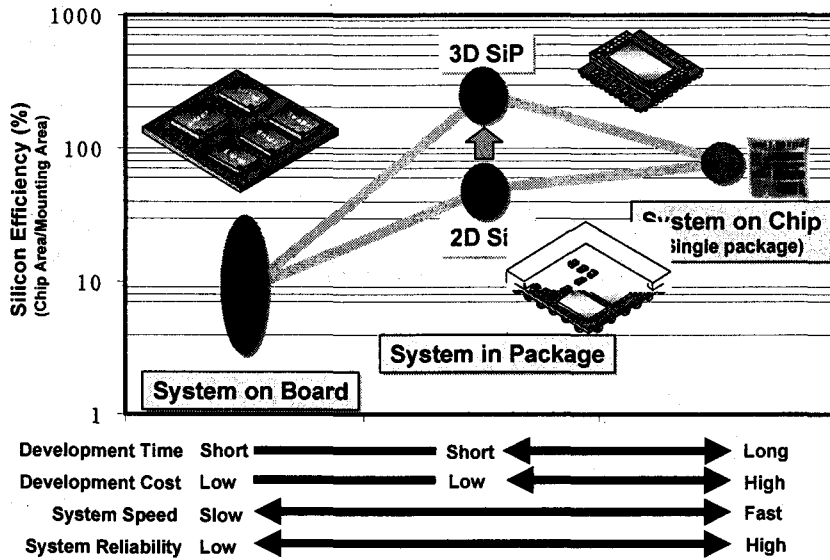
## Toward the 3D-SiP Era with New Technologies

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## Toward the 3D-SiP Era



## Features and Silicon Efficiency of SoC, 2D and 3D-SiP, and SoB



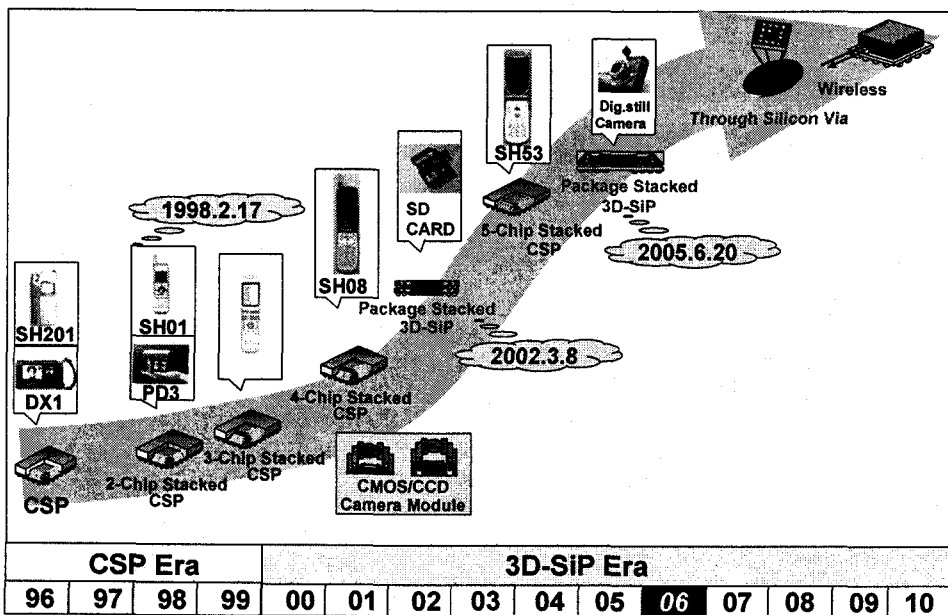
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## Rapidly Evolving 3D-SiP Technology



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## Chip stack and Package stack

### Stacked Die vs. PoP – Trade Offs

Stacked Die 	PoP 
<p><b><u>Prospects</u></b></p> <ul style="list-style-type: none"> <li>• IDM ownership</li> <li>• Smaller body size and lower package profile</li> </ul>	<p><b><u>Prospects</u></b></p> <ul style="list-style-type: none"> <li>• OEM Ownership</li> <li>• Flexible memory sources, facilitate memory capacity increases</li> <li>• Tested at individual package level for Known Good Device</li> </ul>
<p><b><u>Concerns</u></b></p> <ul style="list-style-type: none"> <li>• KGD required for high product yield</li> <li>• Single-sourced product</li> <li>• New development needed to change a device or handle die shrink</li> <li>• Compound yield and multi test</li> </ul>	<p><b><u>Concerns</u></b></p> <ul style="list-style-type: none"> <li>• Slightly larger / thicker Package stack</li> <li>• Co-design for bottom and top packages</li> <li>• Infrastructure for package stacking</li> </ul>

Source: Amkor Technology, Panasonic Factory Solutions, Senju Metal Industry, Sharp (ECTC2006)

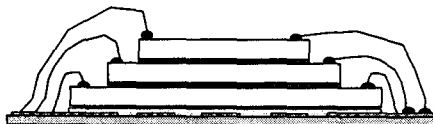
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## Chip Stacking Technology

**Pyramid Stacking Structure**  
Normal Wire Bonding (Left)  
and Reverse Wire Bonding (Right)



**Over Hanging Stacking Structure**  
Chip on Wire (Cow) technology






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## Overview of Package-Stacking Technologies (Logic + Memory)

	Fan-out+Solder Ball Interconnect (Sharp etc) 	Tape Substrate Interconnect (A) 	ISM+ Wire Bond Interconnect (B) 
<b>Ownership</b>	<b>Customer</b>	<b>Logic Manufacture</b>	<b>Logic Manufacture</b>
<b>Ex. Package</b>	<b>14X14</b>	<b>13X11 0.65P 188</b>	<b>14X14 13X13</b>
<b>Top Memory</b>	0.5P(2S/3R) 162max		
<b>Bottom Logic</b>	0.5P(4S/2R) 200max 0.5P 436max (0.65P) (385max)	14X14 0.65P 336	
<b>Package Height (1Logic+2memory)</b>	<b>1.60max</b>	<b>1.55max</b>	
<b>Production Line</b>	<b>Conventional +</b>	<b>Conventional ++</b>	<b>Conventional ++</b>
<b>Die Shrink</b>	○	○	○
<b>Memory Testing</b>	△ New Socket	○ Current Testing System	× New C/K, New Socket
<b>Multi-layer Stacking</b>	○	△	×
<b>Thermal performance</b>	△	△	△
<b>Total Assessment</b>	○	△	×

○ Good  
△ Fair  
× Poor

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## Features of PoP and PiP

PoP	PiP
<ol style="list-style-type: none"> <li>1. Uses solder ball (SMT infrastructure) to interconnect individual package.</li> <li>2. Products are controlled by the customer.</li> <li>3. Diverse combinations are available without additional infrastructure.</li> <li>4. Packages are usually larger in size.</li> </ol>	<ol style="list-style-type: none"> <li>1. Uses wire bonding to interconnect individual package.</li> <li>2. Products are controlled by the Logic manufacture.</li> <li>3. Diverse combinations are available with additional ISM.</li> <li>4. Packages are usually smaller in size.</li> </ol>

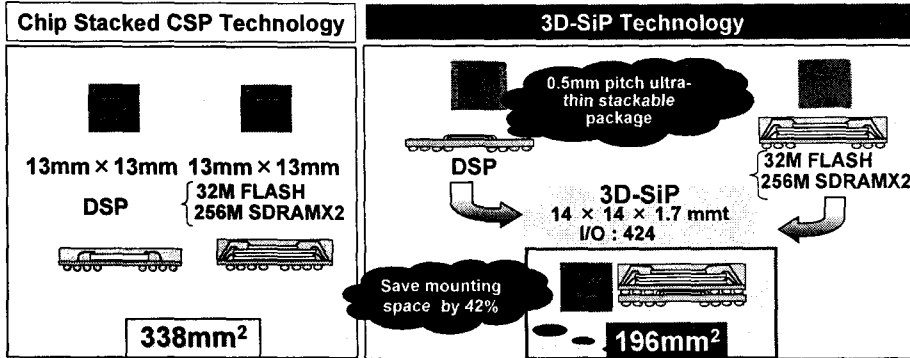
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## Examples of PoP-based 3D-SiP Products for DSCs



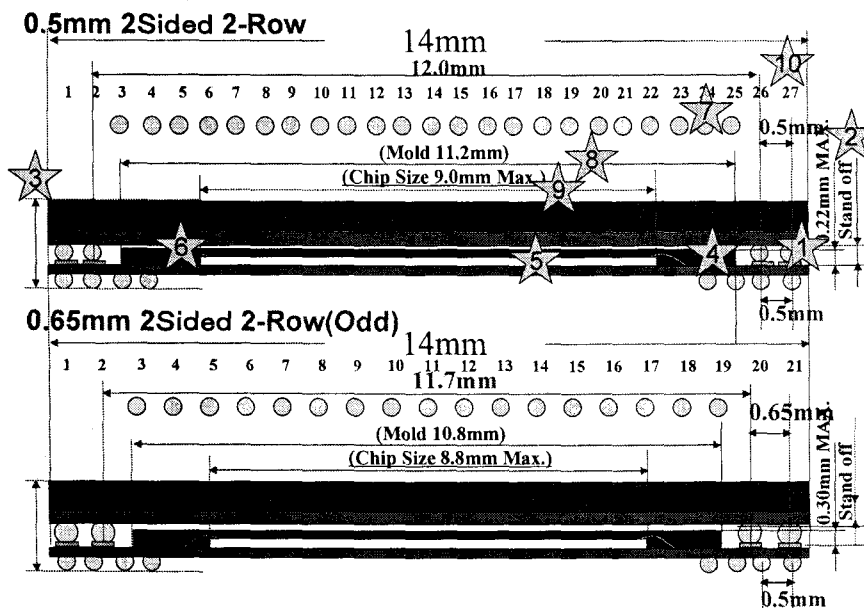
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## Interrelations between PoP Package Dimensions



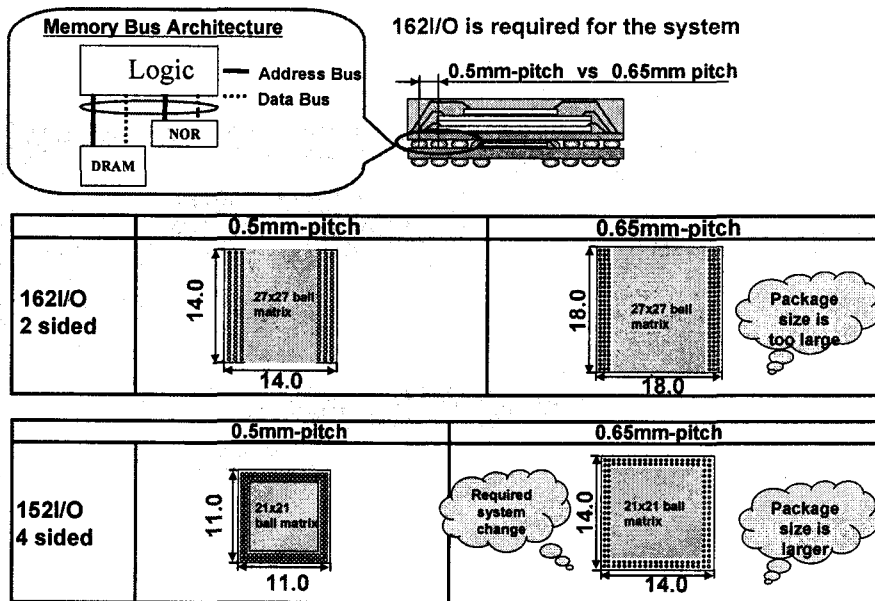
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## Effects on Package Size of 0.5-mm and 0.65-mm Pitch Interconnects



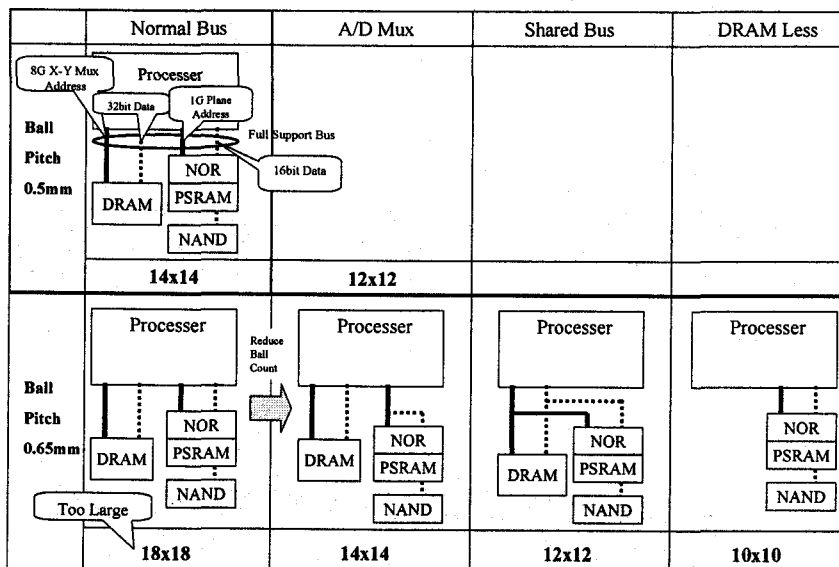
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## Bus Design vs. Package Size of 3D-SiP



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## 2-Sided vs. 4-Sided Ball Layout of 3D-SiP

① Case of the bonding pad combination which is placed in cross direction



- ①-1: In the case of dual bus combination ⇒ Option A is better than option B
- ①-2: In the case of single bus combination ⇒ No significant differences

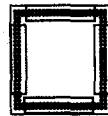
② Case of the bonding pad combination which is placed in same direction



- ②-1: Case of dual bus combination ⇒ Option B is better than option A
- ②-2: Case of single bus combination ⇒ No significant differences

Option A  
(Four-side type)

Option B  
(Two-side type)



NOR+SRAM  
DRAM

Bottom Package Top View

New Mold System



Conventional Mold System



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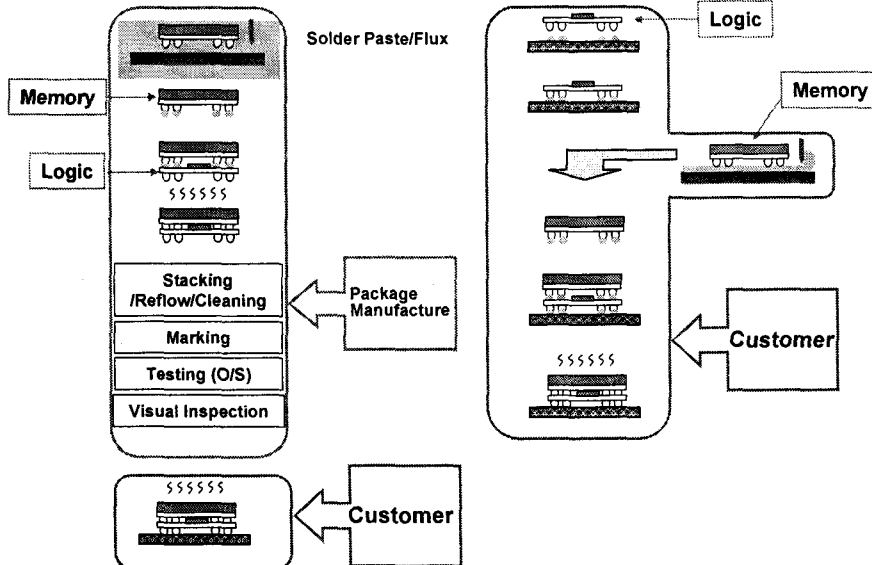
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## PoP Package-Stacking Methods

Pre-Stacking

SMT Stacking



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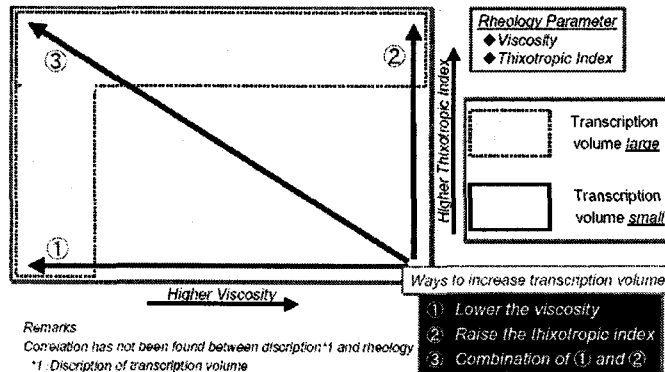
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## Optimization of Solder Paste is Required

Transcription property and solderability effected by **rheology**

Transcription volume VS Rheology



Source: Senju Metal Industry (MAP & RTS 2005)

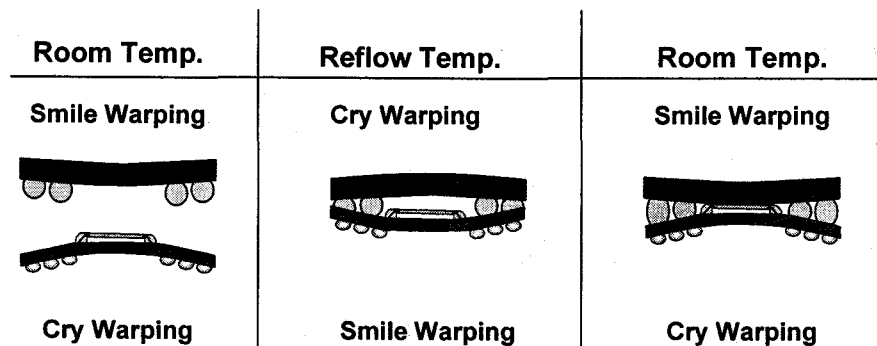
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## Typical PoP Package Warping Behavior



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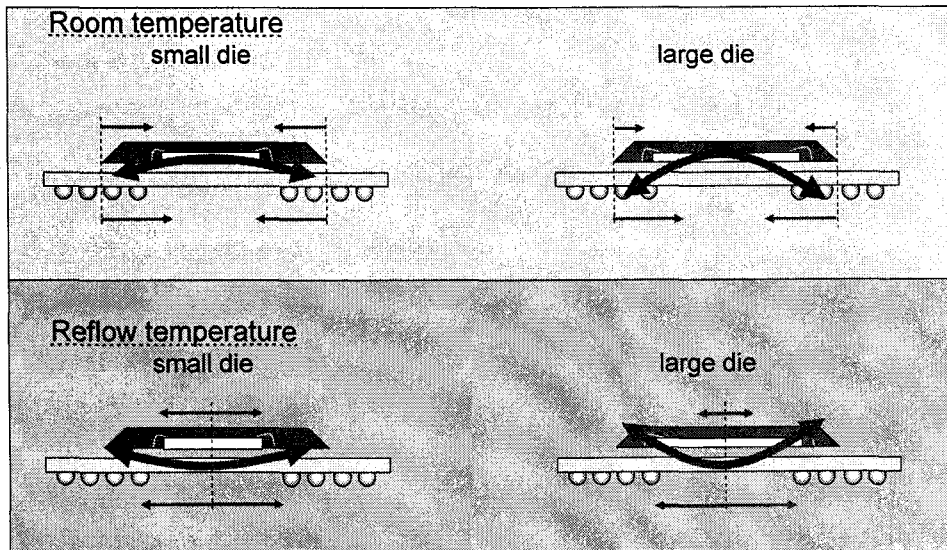
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## The Chip Size Affects the Bottom CSP Warpage Behavior

Source: ECTC2006



Source: Amkor Technology, Panasonic Factory Solutions, Senju Metal Industry, Sharp (ECTC2006)

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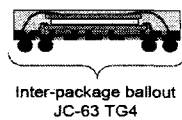
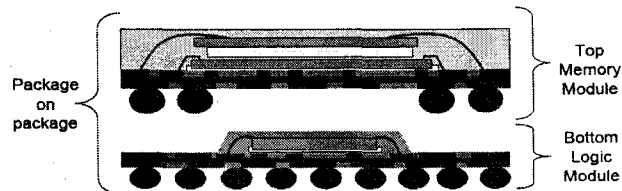
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## JEDEC Standard No.21-C

JEDEC Standard No. 21-C  
Page 3.12.2 - 2



Inter-package ballout is dependent on:

- Package size
- Bus architecture
- Supported memory die

Figure 3.12.2-1 - Inter-Package Ballout

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## Summary of Standardization of PoP Memory from JEDEC JC-63 JEDEC Standard No.21-C

	Package	Memory Bus Supported
1	11 mm x11 mm Package 0.65 mm Ball Pitch 2 Perimeters of Balls - 112 Total Balls	x16 Nor +x16(p)SRAM +x16 SDRAM +x16 NAND shared databus
2	12 mm x12 mm Package 0.65 mm Ball Pitch 2 Perimeters of Balls - 128 Total Balls	x16 Nor +x16(p)SRAM + x16 SDRAM + x16 NANDshared databus
3	15.00 mm x15 mm Package 0.65 mm Ball Pitch 2 Perimeters of Balls - 160 Total Balls	Options Bus A Bus B A: x16 NOR+PS+NAND x16 DDR B: x16A/D NOR+PS+NAND x16 DDR C: x32A/D NOR+PS+NAND x16 DDR D: x16A/D NOR+PS+NAND x32 DDR
4	16.00 mm x16 mm Package 0.65 mm Ball Pitch 2 Perimeters of Balls - 176 Total Balls	Options Bus A Bus B A: x16 NOR+PS+NAND x16 DDR B: x16A/D NOR+PS+NAND x16 DDR C: x32A/D NOR+PS+NAND x16 DDR D: x16A/D NOR+PS+NAND x32 DDR
5	14 mm x14 mm Package 0.5 mm Ball Pitch 2 Perimeters of Balls - 208 Total Balls	x16 Nor +x16(p)SRAM and x32 SDRAM Split Data Bus
6	14mm x14mm Package 0.65mm Ball Pitch 21 x21 Ball Matrix 152 FBGA	Options Bus A Bus B Bus C AA x32 (Lower 16 bits) x32 (Upper 16 bits) x16 NAND M-DRAM + NOR M-DRAM + NOR AB x32 (Lower 16 bits) x32 (Upper 16 bits) NOR x16 NAND NOR +pSRAM + pSRAM AC x16 M-DRAM x16 ADQ NOR x16NAND AD None x16 ADQ NOR +pSRAM x16NAND
7	13mm x13mm Package 0.65mm Ball Pitch 19 x19 Ball Matrix 136 FBGA	Options Bus A Bus B Bus C AA x32 (Lower 16 bits) x32 (Upper 16 bits) x16 NAND M-DRAM + NOR M-DRAM + NOR AB x32 (Lower 16 bits) x32 (Upper 16 bits) NOR x16 NAND NOR +pSRAM + pSRAM AC x16 M-DRAM x16 ADQ NOR(A24 Max) x16NAND AD None x16 ADQ NOR +pSRAM x16NAND

## JEDEC Standard No.21-C

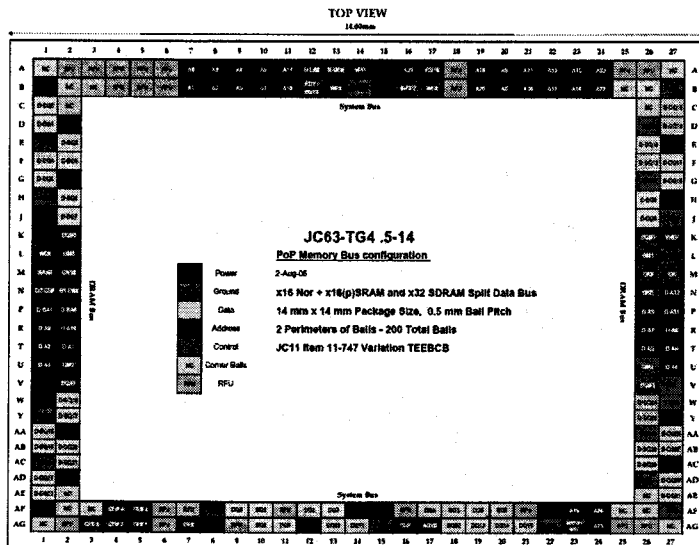


Figure 3.12.2-10  
Ball Outline - 200-Ball BGA, 0.5 mm Pitch, 14 mm x 14 mm Package

## JEDEC PUBLICATIONS 95 Design Guide 4.22

JEDEC DESIGN STANDARD

DESIGN REQUIREMENTS FOR OUTLINES OF  
SOLID STATE AND RELATED PRODUCTS

JEDEC PUBLICATION 95

Design Guide 4.22

Fine-pitch, Square Ball Grid Array Package  
(FBGA) Package-on-Package (PoP)

JEDEC  
SOLID STATE TECHNOLOGY ASSOCIATION

Date: November 2005  
Item: 11.02-7265

Issue: A

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## Current and Future Issues in PoP

- Full-fledged use of PoP only have just begun, many issues still remain, such as
  - Device supply
  - Expansion of standardization
  - Stacking infrastructure improvement
- There are also fundamental issues:
  - Current PoP packages are stacked with a fan-out structure, package size is larger than in chip stacking,
  - The top package is often memory, for which a chip stack package is used, while a single chip is used for the bottom package to keep package height low.



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## New Stack Interconnect Technology

Chip and package stacking have already been adopted commercially and are core technologies in 3D-SiP, but new technologies are starting to gain attention. These can be divided into the following three categories:

### 1. Through-Silicon Via Technology

- Chip on Chip
- Chip on Wafer
- Wafer on Wafer

### 2. Wireless Interconnect Technology

- Inductive Coupling
- Capacitive Coupling
- Electromagnetic Wave Coupling

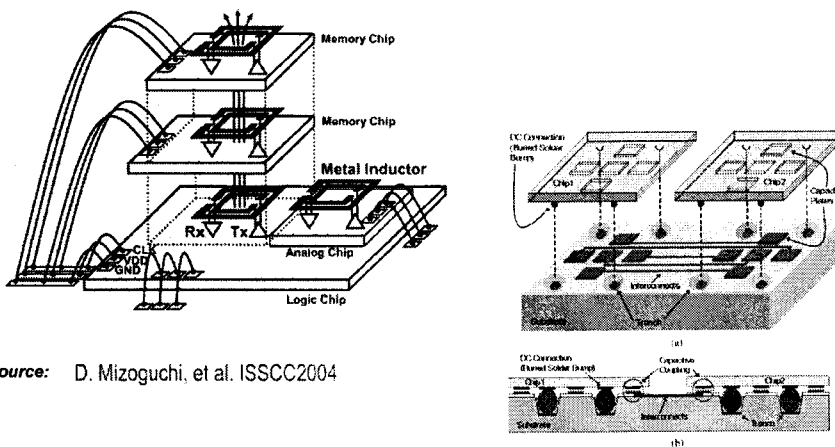
### 3. Optical Interconnect Technology

## Categories of New Interconnect Technologies

	Monolithic	Interchip	Board Level Interconnect
Wired Interconnect	Multilayer Metal Transmission Line	Bonding Wire Through Si Via	PCB Transmission Line Cable: coaxial cable, Flat
Wireless Interconnect		Inductive (L) Coupling - Short Distance Capacitive (C) Coupling - Very Short Distance Electromagnetic Coupling (Antenna) - Long Distance	
Optical Interconnect	Integrated Optical Device Planar waveguide	Optical Circuit Board	Optical Fiber

Source: Iwata (Hiroshima Univ.)

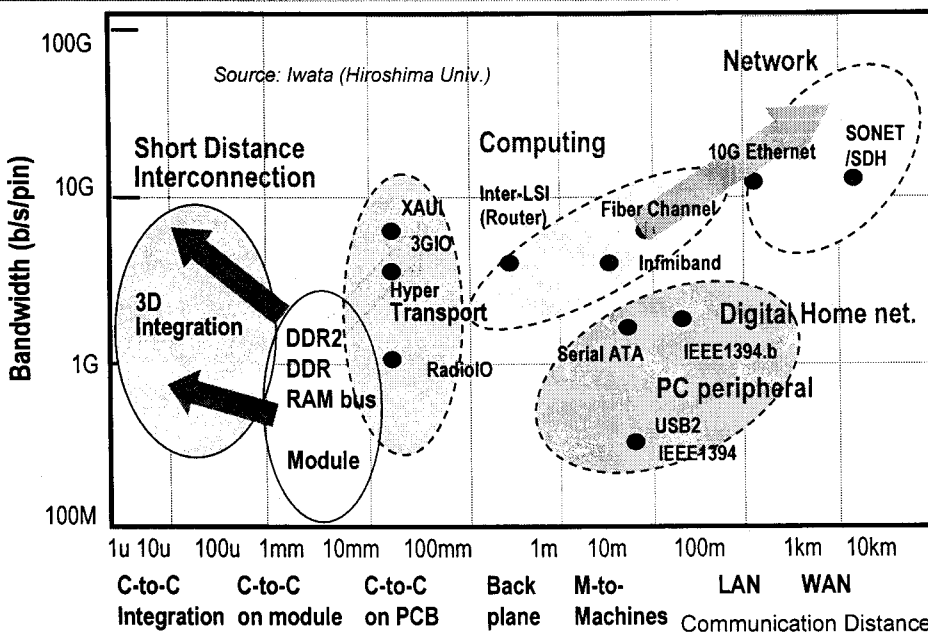
## Examples of Inductive Coupling and Capacitive Coupling



Source: D. Mizoguchi, et al. ISSCC2004

Source: IEEE JOURNAL OF SOLID-STATE CIRCUITS, VOL. 41, NO. 1, JANUARY 2006  
 Lei Luo, John M. Wilson, Stephen E. Mick, Jian Xu, Liang Zhang, and Paul D. Franzon, *Fellow, IEEE*

## 3D Integration is a Very Short Distance Interconnection



## Characteristics of New Interconnect Technologies

	Interconnect Technology (Distance)	Data Rate	Power Consumption	Interconnect Density	Process	Cost	Chip Testing
Wire	Bonding Wire	X (2Gbps)	X	X	△	△	△
	Through Si Via	○ (8Gbps) <small>Iwata (Hiroshima University)</small>	○	○	X	X	△
Wireless	Inductive Coupling	○ (10Gbps)	○	△	○	○	○

○ Good  
 △ Fair  
 X Poor

*Source: Iwata (Hiroshima Univ.)*

## Conclusion

1. In the near future, these technologies will contribute new types of 3D-SiP.
2. However, whether TSV or some other technology will become dominant, and which technologies will be used in which applications depends on the results of R&D yet to come.
3. It is hoped that when these new technologies become the mainstream, they will produce 3D-SiPs that surpass SoC and usher in a new generation in the semiconductor industry.